

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**
(Not for submission under 37 CFR 1.99)

Application Number	10588981
Filing Date	2006-08-10
First Named Inventor	RODERICK BOSWELL
Art Unit	2881
Examiner Name	NOT YET ASSIGNED
Attorney Docket Number	F146

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1	LEUNG, KA-NGO, "Plasma sources for electrons and ion beams," J. Vac. Sci, Technology B, Nov/Dec 1999, Vol. 17, No. 6., pages 2776-2778.	<input type="checkbox"/>
2	MATHEW, JOSE V., ET AL., "Subcutoff microwave driven plasma ion sources for multielemental focused ion beam systems," Review of Scientific Instruments, 2008, Vol 79, 5 pages.	<input type="checkbox"/>
3	ONO, L.K., ET AL., "A Compact Gas Cluster Ion Beam Source of QSEC," 2003, 4 pages.	<input type="checkbox"/>
4	Singleton Accelelor Systems: Coaxial and In-Line Positive Ion Accelerators, 6 pages.	<input type="checkbox"/>

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